

Notice of References Cited		Application/Control No. 10/566,412	Applicant(s)/Patent Under Reexamination RUHE ET AL.	
		Examiner ROBERT EOM	Art Unit 1797	Page 1 of 1

U.S. PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
*	A	US-6,670,286	12-2003	Yang et al.	438/780
	B	US-			
	C	US-			
	D	US-			
	E	US-			
	F	US-			
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	H	US-			
	I	US-			
	J	US-			
	K	US-			
	L	US-			
	M	US-			

FOREIGN PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
	N					
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NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	Ruther et al., Surface Conductivity of a CMOS Silicon Nitride Layer, Oct. 2003, Proceedings of IEEE Sensors, Volume 2, pg 920-925.
	V	Usui et al., Ionization-Assisted Deposition of Alkyacrylate and Fluorinated Alkylacrylate Polymer Thin Films, June 2003, Proceedings of the conference on Properties and Applications of Dielectric Materials, Volume 1, pg 104-107.
	W	
	X	

*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.